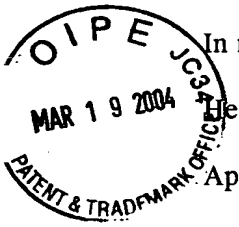


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re Patent Application of)

Helen H. ZHU et al.)

Application No.: 09/820,694)

Filed: March 30, 2001)

For: METHOD OF PLASMA ETCHING)
SILICON NITRIDE)

) Group Art Unit: 2823

) Examiner: J. J. Maldonado

) Confirmation No.: 7374

REQUEST FOR INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The undersigned requests an interview with the Examiner before issuance of a first action final rejection. Please contact the undersigned at the (703) 838-6560.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Date March 19, 2004
P.O. Box 1404
Alexandria, VA 22313-1404
(703) 836-6620

By: _____


Peter K. Skiff
Registration No. 31,917

VA 83939.1